1/11 <u>100</u> **BEGIN DISPOSE SENSOR ON MEMS OPTICAL ELEMENT** 102 **EXPOSE SENSOR TO** 104 **MAGNETIC FIELD** 106 **MEASURE CHANGE IN A PROPERTY OF THE** SENSOR AS POSITION OF MEMS OPTICAL **ELEMENT CHANGES WRT MAGNETIC FIELD**

FIG. 1

ΕŅD

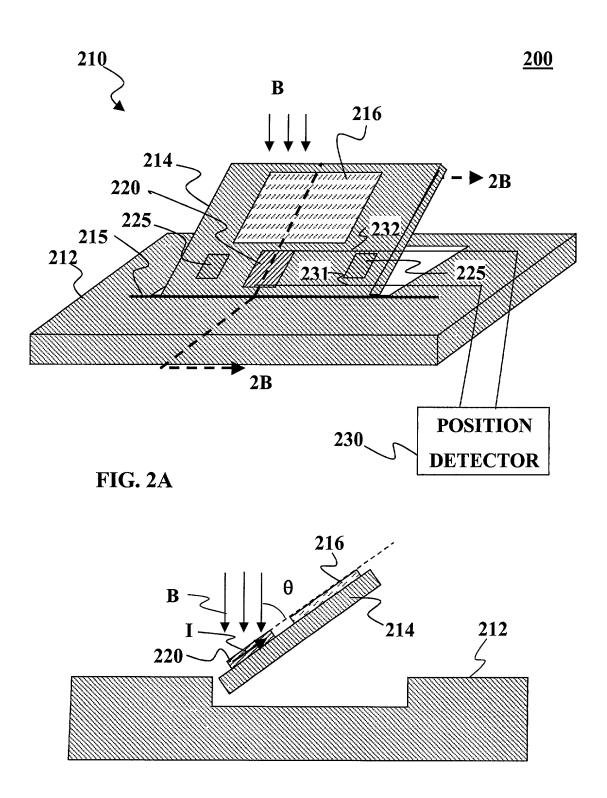


FIG. 2B

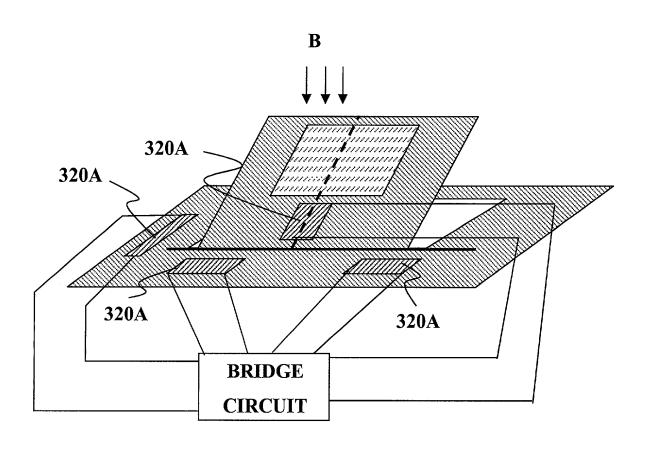


FIG. 3A

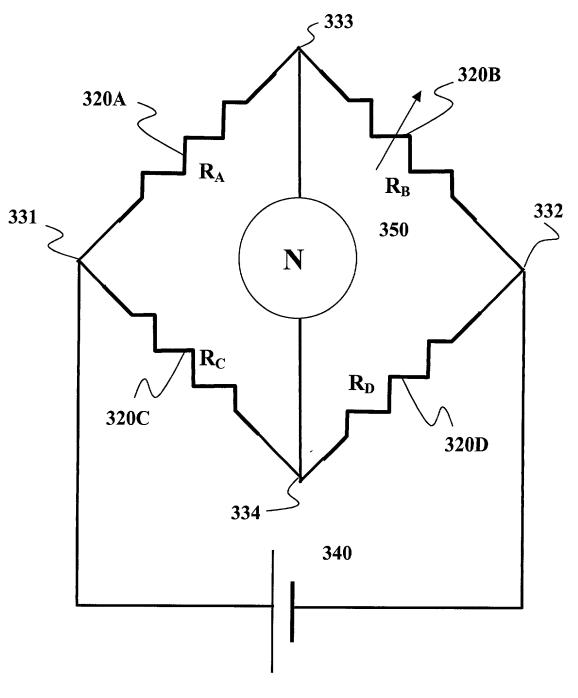


FIG. 3B

5/11



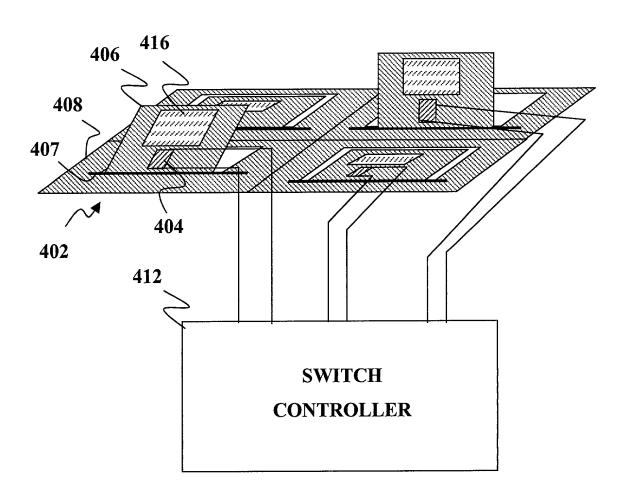


FIG. 4

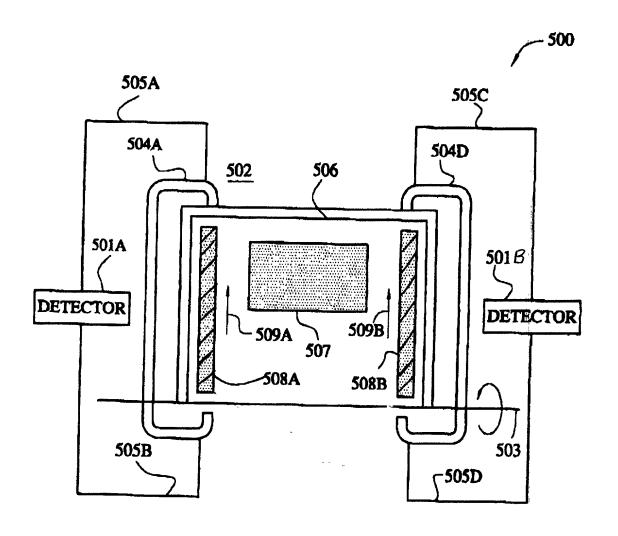


FIG. 5A



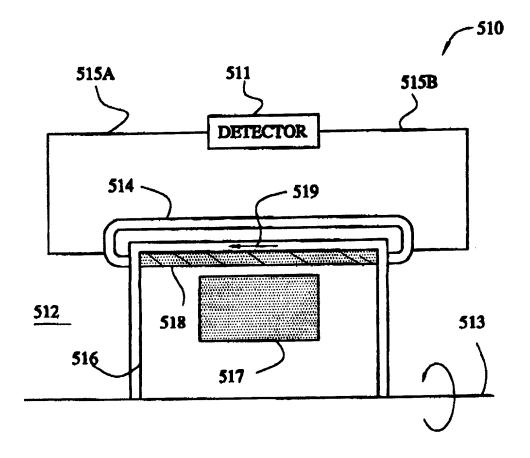


FIG. 5B

8/11

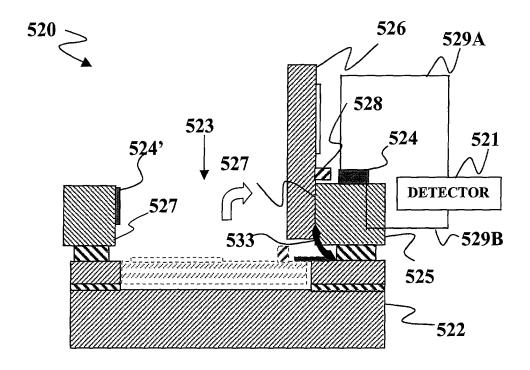
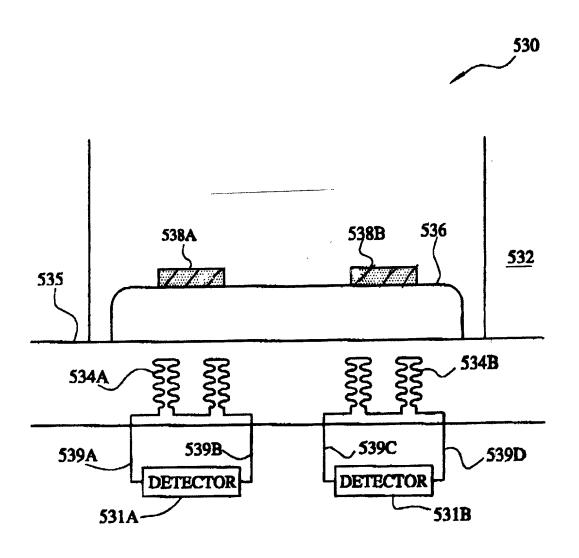


FIG. 5C

9/11



FIG, 5D

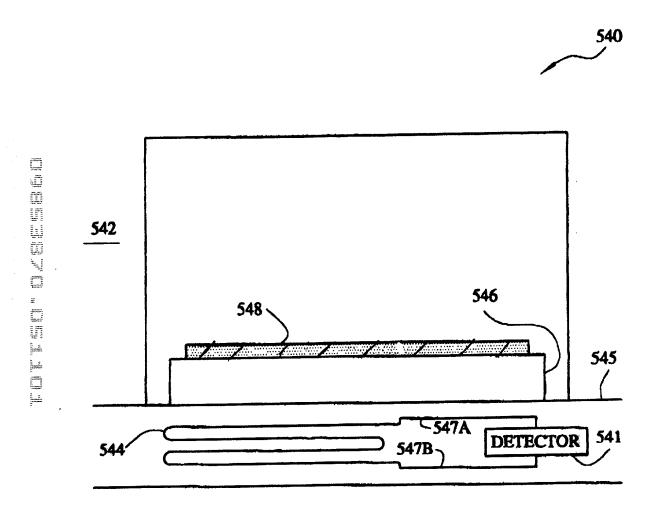


FIG. 5E

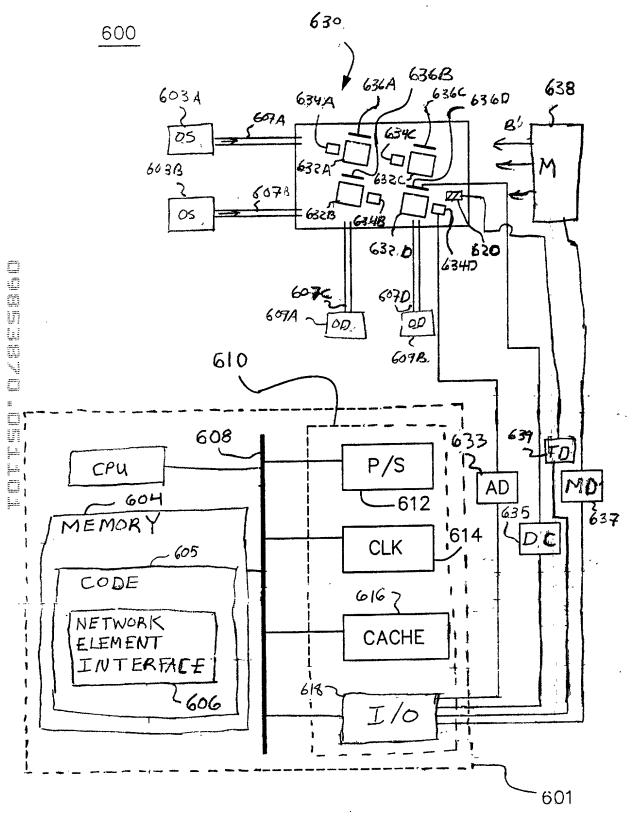


Fig. 6